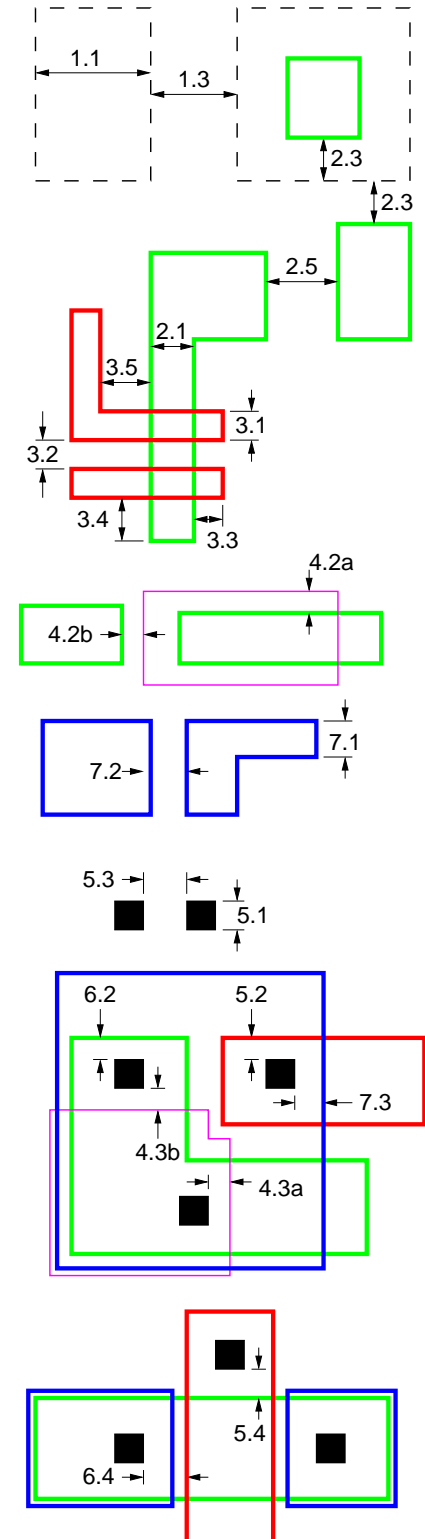


# ELEC3025 Sample Design Rules

## Simplified Design Rules for a 0.2um CMOS process

Design Rule	Distance (microns)
<b>N-well</b>	
1.1 Minimum n-well width	1.2
1.3 Minimum n-well spacing	0.6
<b>Active Area</b>	
2.1 Minimum active area width	0.3
2.3 Minimum well edge to active area	0.6
2.5 Minimum active area spacing	0.4
<b>Polysilicon</b>	
3.1 Minimum polysilicon width	0.2
3.2 Minimum polysilicon spacing	0.4
3.3 Minimum polysilicon extension beyond gate	0.25
3.4 Minimum source/drain length	0.4
3.5 Minimum polysilicon spacing to active area	0.1
<b>P implant</b>	
4.2a Minimum p implant enclosure of active area	0.2
4.2b Minimum p implant spacing to active area	0.2
<b>Metal 1</b>	
7.1 Minimum metal 1 width	0.3
7.2 Minimum metal 1 spacing	0.3
<b>Contact Window</b>	
5.1 Minimum/maximum contact dimension	0.2
5.3 Minimum contact spacing	0.4
4.3a Minimum p implant enclosure of contact	0.15
4.3b Minimum p implant spacing to contact	0.15
5.2 Minimum polysilicon enclosure of contact	0.15
6.2 Minimum active area enclosure of contact	0.15
7.3 Minimum metal 1 enclosure of contact	0.1
5.4 Minimum polysilicon contact spacing to active area	0.2
6.4 Minimum active area contact spacing to polysilicon gate	0.2



\* This is not a complete set of design rules but is sufficient for most simple cell designs \*